08/12/2008

UNIU40.005APC PATENT

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

**Applicant** 

Masahiko NAKAMORI, et al.

App. No

10/536621

Filed

May 26th, 2005

For

POLISHING PAD AND METHOD OF

PRODUCING SEMICONNDUCTOR

**DEVICE** 

Examiner

Sylvia R. MacArthur

Art Unit

1792

Conf#

9275

## AMENDMENT AFTER FINAL

## Mail Stop AF

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

## Dear Sir:

In response to the Office Action mailed June 2<sup>nd</sup>, 2008, please reconsider the present application in light of the following amendments and comments.

**Amendments to the Claims** are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 5 of this paper.